



Atty Docket No. Serial No. U.S. Department of Commerce, Patent and Trademark Office M-10693 US Unknown INFORMATION DISCLOSURE STATEMENT BY APPLICANT Applicants: Steve Biellak, et al. (Use several sheets if necessary) Filing Date: June 26, 2001 Group: Unknown-U.S. Patent Documents Filing Date *Examiner Document Number Subclass If Appropriate Initial Date Name Class 4,449,818 5/1984 Yamaguchi AA 4,794,265 AB 12/1988 Quackenbos et al. AC 4,893,932 1/1990 Knollenberg AD 4,898,471 2/1990 Stonestrom et al. AE 4,929,845 5/1990 Amir et al. 10/1991 Katzir AF 5,058,982 2/1995 Allen et al. 5,389,794 AG ΑH 5,424,838 6/1995 Siu ΑI 6/1996 Nikoonahad et al. 5,530,550 7/1997 Yasutake et al. AJ 5,650,614 Vaez-Iravani AK 5,798,829 8/1998 5/1995 Gross et al. AL5,416,594 AM 6,201,601 B1 3/2001 Vaez-Iravani et al. 09/746,141 12/21/00 AN **Foreign Patent Documents** Translation Yes Document Date Country Class Subclass No X AO WO97/33158 9/1997 International AP EP0624787 11/1994 Europe X X AQ DE4123916 1/1992 German WO97/12226 4/1997 X AR International ART (Including Author, Title, Date, Pertinent Pages, Etc.) "Surface Inspection System for Estimation of Wafer," Y. Yatsugake et al., Hitachi Electronics AS Engineering Technical Report, Vol. 11, January 1996, pp. 21-26 Figure, Hitachi Electronics Engineering Co., Ltd., presented by Etsuro Morita of Mitsubishi Materials AT Silicon Corp. in a presentation entitled "Exploration of COP and COP Defect Crystal Originated 'Particles'," at the 6th International Workshop on 300 Millimeter Wafers on 12/5/1996 in Makuhari, Japan Partial European Search Report dated October 18, 2000 AU 22102 Examiner Date Considered *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.